

I HEREBY CERTIFY THAT THIS CORRESPONDENCE IS BEING DEPOSITED WITH THE UNITED STATES POSTAL SERVICE AS FIRST CLASS MAIL IN AN ENVELOPE ADDRESSED TO: THE COMMISSIONER FOR PATENTS, P.O. Box 1450, Alexandria, VA 22313, On Date of Deposit: 04/18/2005.

Person Making Deposit: Robert Faber

Robert Faber

Signature

4-18-05

Date

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In re Application of:**

Rosenbluth, et al.

**Application No.:** 10/783,938

**Filed:** 02/20/2004

**For:** Fast Model-Based Optical Proximity Correction

**)Attorney Docket No.** FIS920040011US1

**)Examiner:** Not yet assigned

**)Group Art Unit:** 2873

**)Date:** April 18, 2005

The Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313

**INFORMATION DISCLOSURE STATEMENT**

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the document listed on the enclosed Form PTO-1449. The Examiner's attention is directed to the following US Publications.

FIS920040011US1

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04/22/2005 DTESSEM1 00000083 090458 10783938

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<u>US Publications:</u>	<u>Date</u>	<u>Author</u>
"Method Of Measuring The Spatial Resolution Of A Photoresist"	2002	J.A. Hoffnagle, et al.
"Reduction Of ASIC Gate-Level Line-End Shortening By Mask Compensation"	1995	J. Garofalo, et al.
"Improved Modeling Performance Wuth An Adapted Vectorial Formulation Of The Hopkins Imaging Equation"	2003	K. Adam, et al.
" Simulation Of Imaging And Stray Light Effects In Immersion Lithography"	2003	S. Hoffman, et al.

In accordance with 37 C.F.R. § 1.98(a)(2)(iii), a copy of the listed US Publications are enclosed..

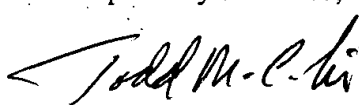
The Commissioner is authorized to charge to Deposit Account No. 09-0458 the amount to cover the fee under 37 C.F.R. § 1.17(p). Any additional fees due or overpayments should also be charged or credited to Deposit Account No. 09-0458.

**CONCLUSION**

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned agent may be reached by telephone at (845)894-6919. All correspondence should continue to be directed to the address listed below.

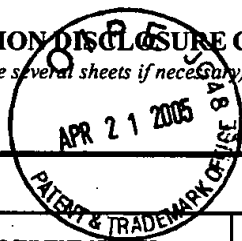
Respectfully submitted,

 4/15/2005

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<b>INFORMATION DISCLOSURE CITATION</b> <i>(Use several sheets if necessary)</i>	Docket Number (Optional) <b>FIS920040011US1</b>	Application Number <b>10/783,938</b>
Applicant(s) <b>Rosenbluth, et al.</b>		
Filing Date <b>02/20/2004</b>		Group Art Unit <b>2873</b>



U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

U.S. PATENT APPLICATION PUBLICATIONS							
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO

OTHER DOCUMENTS		(Including Author, Title, Date, Pertinent Pages, Etc.)
		1) "Method Of Measuring The Spatial Resolution Of A Photoresist" - J.A. Hoffnagle, et al. 2002 Optical Society of America - p. 1776 2) "Reduction Of ASIC Gate-Level Line-End Shortening By Mask Compensation" - J. Garofalo, et al. SPIE Vol. 2440 - Optical/Laser Microlithography VIII - p. 171
		3) "Improved Modeling Performance With An Adapted Vectorial Formulation Of The Hopkins Imaging Equation" - Adam, et al. - p. 78-91 4) "Simulation Of Imaging And Stray Light Effects In Immersion Lithography - Hafeman, et al. SPIE Vol. 5040 - Optical Microlithography XVI, ed. Anthony Yen (2003), p. 700

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.